a ground electrode in contact with each of the plurality of cylindrical rollers;

an opposing electrode opposing the ground electrode;

a vacuum chamber;

an introducing means for introducing a gas into the vacuum chamber;

a gas evacuation means; and

an energy supplying means for supplying an energy to make a plasma from the gas;

C1

wherein the flexible substrate is located between the ground electrode and the opposing electrode,

wherein center axes of the plurality of cylindrical rollers run parallel to each other,

Cont

wherein the substrate is in contact with each of the plurality of cylindrical rollers with a wrap angle kept positive to create a force in a direction pressing the flexible substrate against the plurality of cylindrical rollers,

wherein the ground electrode act as a conveyance supporting portion,

wherein the plurality of cylindrical rollers are provided with a heater.

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3. (Amended) A film formation apparatus for a flexible substrate, said film formation apparatus comprising:

C2

at least two rollers for continuously conveying the flexible substrate from one end to the other end;

a plurality of cylindrical rollers being provided between the one end and the other end along an arc with a radius R;

a ground electrode in contact with each of the plurality of cylindrical rollers;

an opposing electrode opposing the ground electrode,

wherein the flexible substrate is located between the ground electrode and the opposing electrode,

wherein center axes of the plurality of cylindrical rollers run parallel to each other,

wherein the substrate is in contact with each of the plurality of cylindrical rollers with a wrap angle kept positive to create a force in a direction pressing the flexible substrate against the plurality of cylindrical rollers,

wherein the ground electrode act as a conveyance supporting portion,

wherein the plurality of cylindrical rollers are provided with a heater.

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Please add the following new claims 10-15.

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10. An apparatus comprising:

a plurality of cylindrical rollers arranged along an arc

wherein center axes of the plurality of cylindrical rollers run

parallel to each other;

a flexible substrate passing along said plurality of cylindrical rollers wherein said flexible substrate is curved so that said substrate has a concave surface in contact with said plurality of cylindrical rollers and a convex surface opposite to said concave surface; and

an electrode opposed to said plurality of cylindrical rollers with said flexible substrate disposed therebetween.

11. The apparatus according to claim 10 wherein said plurality of cylindrical rollers are grounded and said electrode is connected to a high frequency power supply.

12. The apparatus according to claim 10 wherein said apparatus is a plasma CVD apparatus.

13. A method comprising:

providing a plurality of cylindrical rollers arranged along an arc in a chamber wherein center axes of the plurality of cylindrical rollers run parallel to each other;

providing an electrode opposed to said plurality of cylindrical rollers in said chamber;

moving a flexible substrate from a first roller to a second roller wherein said flexible substrate passes through a space

between said plurality of cylindrical rollers and said electrode;

introducing a gas into said chamber; and

applying an electrical energy to said electrode to form a plasma of said gas,

wherein said flexible substrate is curved so that said flexible substrate has a concave surface being in contact with said plurality of cylindrical rollers and a convex surface opposite to said concave surface.

14. The method according to claim 13 wherein a film is formed from said plasma.

15. The method according to claim 13 wherein said flexible substrate is in contact with said plurality of cylindrical rollers with a wrap angle kept positive.